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North-China Electrical Power University National San Luis Gonzaga de Ica

Implantation optimization for 1200 V Sic MPS with ultra-low leakage tics current and high surge current capability

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- Introduction of SiC MPS
- ➢ Simulation of 1200 V/20 A MPS
- Fabricating and Comparison
- > Summary



Introduction of SiC MPS





Highly preferred for high voltage and high power applications

Millan, J., et. Al, A survey of wide bandgap power semiconductor devices. IEEE transactions on Power Electronics, 29(5), 2155-2163, 2013.



















Simplified fabricating flow



P+ ring implantation

Ohmic contact Schottky contact Laser anneal for back side Ohmic



Fabricating and Comparison







Fabricating and Comparison







Fabricating and Comparison









Surge current testing



Surge current capability comparison under different temperature





IV testing under high current







Turning off testing



Similar turning off curves for the three diode







1200 V/20 A SiC MPS

Features

Ultra-low leakage current

High surge current capability

Without scarifying V_F or other characteristics





Thank you for listening